



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Takashi NAGASE et. al.

Title: METHOD OF MANUFACTURING NANO-GAP ELECTRODE

Appl. No.: 10/662,886

Filing Date: 09/16/2003

Examiner: Ahmed, Shamim

Art Unit: 1765

AMENDMENT AND REPLY UNDER 37 CFR 1.111

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This communication is responsive to the Non-Final Office Action dated June 10, 2005, concerning the above-referenced patent application.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this document.

Remarks/Arguments begin on page 6 of this document.

Please amend the application as follows: